

[0059]

CLAIMS

[0060]

We claim:

1 1. A high purity aluminum alloy with controlled particulate size and
2 distribution of mobile impurities present in said alloy, said high purity aluminum alloy
3 being employed in the manufacture of semiconductor processing apparatus where
4 exposure to corrosive environments would degrade an aluminum alloy which does not
5 exhibit controlled mobile impurity particulate size and distribution, said high purity
6 aluminum alloy having mobile impurity particulates within specific limits so that at least
7 95 % of all particles are 5 μm or less in size, no more than 5 % of said particles range
8 between 20 μm and 5 μm , and no more than 0.2 % of said particles range between 50 μm
9 and 20 μm .

1 2. A high purity aluminum alloy in accordance with Claim 1, wherein no
2 more than 0.1 % of said particles range between 50 μm and 20 μm .

1 3. A high purity aluminum alloy in accordance with Claim 2, wherein no
2 more than 0.1 % of said particles range between 40 μm and 20 μm .

1 4. A high purity aluminum alloy in accordance with Claim 1, wherein no
2 more than 0.2 % of said particles range between 40 μm and 20 μm .

1 5. A high purity aluminum alloy in accordance with Claim 1 or Claim 2,
2 or Claim 3, or Claim 4, wherein said particulates are formed from mobile impurities
3 selected from the group consisting of magnesium, silicon, iron, copper, manganese, zinc,
4 chromium, titanium, and compounds thereof.

1 6. A high purity aluminum alloy in accordance with Claim 1 wherein said

2 alloy includes mobile impurities present at the following concentrations or at lower
3 concentrations, magnesium at 4.0 weight %, silicon at 0.03 weight %, iron at 0.03
4 weight %, copper at 0.07 weight %, manganese at 0.015 weight %, zinc at 0.16 weight
5 %, chromium at 0.07 weight %, titanium at 0.01 weight %, and wherein a total of other
6 impurities present in said aluminum alloy ranges from 0 - 0.1 weight %, with individual
7 other impurities limited to 0 - 0.03 weight % each.

1 7. A high purity aluminum alloy in accordance with Claim 6, wherein said
2 magnesium is present at a concentration ranging between about 3.5 weight % and about
3 4.0 weight %.

1 8. A method of producing a corrosion-resistant article for use in
2 semiconductor processing apparatus, wherein said article comprises a body formed from
3 high purity aluminum alloy, and wherein at least a surface of said body which is to be
4 exposed to a corrosive environment is covered with an aluminum-oxide-comprising film,
5 and wherein at least said surface of said body which is covered said aluminum-oxide-
6 comprising film is an aluminum alloy having mobile impurity particulates controlled
7 within limits so that at least 95 % of all particles are 5 μm or less in size, no more than 5
8 % of said particles range between 20 μm and 5 μm , and no more than 0.2 % of said
9 particles range between 50 μm and 20 μm .

1 9. A method in accordance with Claim 8, wherein no more than 0.1 % of
2 said particles range between 50 μm and 20 μm .

1 10 A method in accordance with Claim 9, wherein no more than 0.1 % of
2 said particles range between 40 μm and 20 μm .

1 11. A method in accordance with Claim 10, wherein no more than 0.2 %
2 of said particles range between 40 μm and 20 μm .

1 12 A method in accordance with Claim 8, wherein said particulates are
2 formed from mobile impurities selected from the group consisting of magnesium, silicon,
3 iron, copper, manganese, zinc, chromium, titanium, and compounds thereof.

1 13. A method in accordance with Claim 8, wherein at least a portion of
2 said aluminum alloy body of said article comprises mobile impurities present at the
3 following concentrations or at lower concentrations, magnesium at 4.0 weight %, silicon
4 at 0.03 weight %, iron at 0.03 weight %, copper at 0.07 weight %, manganese at 0.015
5 weight %, zinc at 0.16 weight %, chromium at 0.07 weight %, titanium at 0.01 weight
6 %, and wherein a total of other impurities present in said aluminum alloy ranges from 0 -
7 0.1 weight %, with individual other impurities limited to 0 - 0.03 weight % each.

1 14. A method in accordance with Claim 13, wherein said magnesium is
2 present at a concentration ranging between about 3.5 weight % and about 4.0 weight %.

1 15. A method in accordance with Claim 8 or Claim 10, or Claim 13 or
2 Claim 14, wherein said corrosion-resistance is with respect to active halogen-containing
3 species.

1 16. A method in accordance with Claim 15, wherein said active halogen-
2 containing species are present in the form of a plasma.

1 17. A method of creating an aluminum oxide protective film on the surface
2 of a high purity aluminum alloy, comprising: exposing said surface of said aluminum

3 alloy to an electrolytic oxidation process during which said surface is immersed as an
4 anode in an acid electrolyte, with a cathode comprised of an aluminum alloy, and
5 wherein a DC current is applied, wherein said acid electrolyte is a water-based solution
6 comprising 10 % to 20 % by weight sulfuric acid and about 0.5 % to 3.0 % by weight
7 oxalic acid, wherein said protective film is created at a temperature ranging from about 5
8 °C to about 25 °C, and wherein an applied current density of said DC current ranges
9 from 5 A/ft² to 36 A/ft².

1 18. A method according to Claim 17, wherein, prior to exposing said
2 aluminum alloy surface to said electrolytic oxidation process, said surface is cleaned by
3 contacting said surface with an acidic solution which includes about 60 % to 90 % by
4 weight of technical grade phosphoric acid, having a specific gravity of about 1.7, and
5 about 1% - 3 % by weight of nitric acid, wherein said cleaning is carried out with said
6 aluminum alloy surface at a temperature in the range of about 100 °C, for a time period
7 ranging from about 30 seconds to about 120 seconds.

1 19. A method in accordance with Claim 18, wherein subsequent to said
2 cleaning of said aluminum alloy surface and prior to said electrolytic oxidation process,
3 said surface is rinsed with a deionized water rinse.

1 20. A method in accordance with Claim 17, or Claim 18, or Claim 19,
2 wherein said aluminum oxide protective film exhibits hexagonal cells having internal
3 pores ranging in size from about 300 Å to about 750 Å in diameter.

1 21. A method in accordance with Claim 17, or Claim 18, or Claim 19,
2 wherein mobile impurity particulates present in said high purity aluminum alloy are
3 limited so that at least 95 % of all particles have particle size of less than 5 μm, no more

4 no more than 5 % of said particles have particle size range between 20 μm and 5 μm , and
5 no more than 0.2 % of said particles have a particle size range between 50 μm and 20
6 μm .

1 22. A method in accordance with Claim 17, or Claim 18, or Claim 19,
2 wherein said high purity aluminum alloy comprises mobile impurities present at the
3 following concentrations or at lower concentrations, magnesium at 4.0 weight %, silicon
4 at 0.03 weight %, iron at 0.03 weight %, copper at 0.07 weight %, manganese at 0.015
5 weight %, zinc at 0.16 weight %, chromium at 0.07 weight %, titanium at 0.01 weight
6 %, and wherein a total of other impurities present in said aluminum alloy ranges from 0 -
7 0.1 weight %, with individual other impurities limited to 0 - 0.03 weight % each.

1 23. A method in accordance with Claim 21, wherein said high purity
2 aluminum alloy comprises mobile impurities present at the following concentrations or at
3 lower concentrations, magnesium at 4.0 weight %, silicon at 0.03 weight %, iron at 0.03
4 weight %, copper at 0.07 weight %, manganese at 0.015 weight %, zinc at 0.16 weight
5 %, chromium at 0.07 weight %, titanium at 0.01 weight %, and wherein a total of other
6 impurities present in said aluminum alloy ranges from 0 - 0.1 weight %, with individual
7 other impurities limited to 0 - 0.03 weight % each.

1 24. A method in accordance with Claim 17, wherein, prior to creating said
2 aluminum oxide protective film on said high purity aluminum alloy surface, said
3 aluminum alloy is heat treated to relieve stress and increase hardness, wherein said heat
4 treatment is carried out at a temperature of 330 °C or at a lower temperature.

1 25. A method in accordance with Claim 18 or Claim 19, wherein prior to
2 creating said aluminum oxide protective film on said high purity aluminum alloy

2 creating said aluminum oxide protective film on said high purity aluminum alloy
3 surface, said aluminum alloy is heat treated to relieve stress and increase hardness,
4 wherein said heat treatment is carried out at a temperature of 330 °C or at a lower
5 temperature.

1 26. A method in accordance with Claim 21, wherein, prior to creating said
2 aluminum oxide protective film on said high purity aluminum alloy surface, said
3 aluminum alloy is heat treated to relieve stress and increase hardness, wherein said heat
4 treatment is carried out at a temperature of 330 °C or at a lower temperature.

1 27. A method in accordance with Claim 23, wherein, prior to creating said
2 aluminum oxide protective film on said high purity aluminum alloy surface, said
3 aluminum alloy is heat treated to relieve stress and increase hardness, wherein said heat
4 treatment is carried out at a temperature of 330 °C or at a lower temperature.